

CV Sami Franssila

1.6.2015



PhD 1995, Helsinki University of Technology, Dept. of Electrical and Communications Engineering. Thesis: "Plasma Etching in Microdevice Fabrication; Thin Film and Process Integration Aspects"

Professor of materials science, Aalto University (neè Helsinki University of Technology), since August 1, 2009.

138 original articles in international peer reviewed journals

4 review articles, 3 book chapters

>200 international conference papers

5 patents

Book: "Introduction to Microfabrication", John Wiley & Sons

Hirsch-index 26 (ISI Web of Knowledge)

Hirsch-index 34 (Google scholar)

13 PhDs supervised to completion, 9 on-going

31 MScs supervised to completion, 5 on-going

24 BSc supervised to completion, 1 on-going

PhD committee member and opponent at Uppsala, Twente, Delft, Vrije Universiteit Brussels, DTU, University of Kuopio

Associate editor of J.MEMS

Reviewer for Advanced Materials, Biomicrofluidics, Lab Chip, Langmuir, Microelectronic Engineering, Microfluidics & Nanofluidics, Sensors and Actuators A & B, Surface and Coatings Technology

Reviewer for ERC grants, 2009, 2013, 2015

Transducers conference-series:

- o member of Technical committee since 2009 (Denver)

- o member of Executive committee since 2011 (Beijing)

Chairman of 24th Micromechanics Europe, 2013 (Espoo, Finland)

Member of tenure track committee, Aalto School of Chemical Technology 2014-2016

Board member, Aalto University professors council 2012-2013

Vice-chair, doctoral programme committee at School of Chemical Technology at Aalto University, 2011-2013

Director of the national graduate school of Chemical Sensors and Microanalytical Systems (CHEMSEM), 2010-2013, and a board member 2002-2009

Elected life member to the Finnish Academy of Technology (Teknillisten tieteidèn akatemia) in 2010